



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:
Davis et al.

Serial No.: 10/628,001

Filed: July 25, 2003

Confirmation No.: 3943

For: Method For Automatic
Determination Of Semiconductor
Plasma Chamber Matching And
Source Of Fault By
Comprehensive Plasma
Monitoring

§ Group Art Unit: 2812

§ Examiner: Unknown

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

CERTIFICATE OF MAILING 37 CFR 1.8	
I hereby certify that this correspondence is being deposited on July 20, 2004 with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450.	
<u>7/20/2004</u>	<u>Atty - Jea</u>
Date	Signature

Dear Sir:

PRELIMINARY AMENDMENT

The commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/7938/ETCH/SILICON/LYC, the fee of \$852 for 3 new independent claims and 33 new total claims. Prior to examination, please amend the above-identified application as follows:

Amendments to the Specification begin on page 2 of this paper. **Amendments to the Claims** are reflected in the listing of claims which begins on page 3 of this paper. **Remarks** begin on page 14 of this paper.